

EUV Lithography Technology, *Ho Chul Kim, Samsung*

Dr. Ho Chul Kim is a research for advanced lithographic technology, R&D department in Samsung Electronics. He is an advanced lithography specialist such as aberration, RET (resolution enhancement technology) and flare since 1998. Recently, he is working on lithography strategy planning including EUV lithography technology. He obtained his Ph. D. and M.S. in Physics at Seoul National University, 1998.

Abstract: As a new lithographic technology, EUV lithography had been introduced and will be used for mass production of 7nm logic devices and beyond. There are several big changes from previous lithographic technology like KrF, ArF and ArF Immersion. Defects, CD control and productivity enhancement became more difficult for EUV lithography. Several approaches to overcome the difficulties at EUV lithography are introduced at this course.